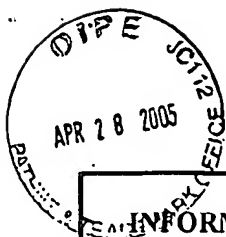


INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P132-US		SERIAL NO. Not Yet Assigned			
		APPLICANT Jim Dunphy, et al.					
		FILING DATE Herewith		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
Dh	U.S. Pub App No. 2003/0002019	1/2/03	Miller				
	U.S. Pub App No. 2002/0056898	5/16/02	Lopes, et al.				
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FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
Dh	"Lubrication of Digital Micromirror Devices" Henck, Tribology Letters 3 (1997) 239-247						
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INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 2 OF 2			ATTY. DOCKET NO. P132-US		SERIAL NO. 10/811,449		
			APPLICANT Dunphy, et al.				
			FILING DATE 3/26/04		GROUP Not Yet Assigned		
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Dle	2004/0012838	1/22/04	Huibers				
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